

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of :
Ki-sang KIM et al. : Attn: Applications Branch
Serial No.: [NEW] : Attorney Docket No.: SEC.584
Filed: January 26, 1999 :
For: MULTI-CHAMBER SYSTEM HAVING COMPACT INSTALLATION SET-UP FOR
AN ETCHING FACILITY FOR SEMICONDUCTOR DEVICE MANUFACTURING

Jc551 U.S. PTO
09/237229



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CLAIM OF PRIORITY

Honorable Assistant Commissioner for Patents and Trademarks,
Washington, D.C. 20231

Sir:

Applicants, in the above-identified application, hereby claim the priority date
under the International Convention of the following Korean application:

Appln. No. 98-14228 filed April 21, 1998

as acknowledged in the Declaration of the subject application.

A certified copy of said application is being submitted herewith.

Respectfully submitted,

JONES, VOLENTINE, STEINBERG & WHITT, L.L.P.

[Handwritten signature]
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Dated: January 26, 1999